

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Takenori HIROSE, et al.

Application No.: 10/081,385

Filed: February 20, 2002

For: FILM THICKNESS MEASURING
METHOD AND APPARATUS, AND THIN
FILM DEVICE MANUFACTURING
METHOD AND MANUFACTURING
APPARATUS USING SAME

Customer No.: 20350

Confirmation No. 9702

Examiner: Hwa S. Lee

Technology Center/Art Unit: 2877

AMENDMENT

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

April 9, 2007

Sir:

In response to the Office Action mailed November 9, 2006, please enter the following amendments and remarks:

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.